



lfw  
PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Tan et al.

**Serial No.:** 10/645,389

**Filed:** August 21, 2003

**For:** APPARATUS, SYSTEMS AND  
METHODS RELATING TO THE  
RECONSTRUCTION OF  
SEMICONDUCTOR WAFERS FOR  
WAFER-LEVEL PROCESSING AND  
RECONSTRUCTED SEMICONDUCTOR  
WAFERS

**Confirmation No.:** 8099

**Examiner:** W. Brewster

**Group Art Unit:** 2812

**Attorney Docket No.:** 2269-5528US  
(02-1052.00/US)

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail on the date of deposit shown below with sufficient postage and in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

April 8, 2005  
Date

Signature

Shirley Dougherty  
Name (Type/Print)

**RESPONSE TO RESTRICTION REQUIREMENT**

Mail Stop Amendment  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This communication is in response to the Restriction Requirement mailed on March 15, 2005, the initial period for response to which expires on April 15, 2005.